

Preventing & Managing Strawberry Anthracnose Resistance

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Strawberry Anthracnose is Fungal



Anthracnose on strawberry fruit

- Caused by *Colletotrichum* spp.
- All parts of the plant (fruit, crowns, leaves, petioles and runners) are susceptible



Anthracnose on strawberry crown



Anthracnose on Strawberry

(Colletotrichum acutatum)







Fungicide efficacy: crown rot

Treatments

Not inoculated
No fungicide
FRAC 11: Abound (8 fl oz/100 gal)
FRAC 9;12: Switch (8 oz/100 gal)
FRAC 7: Kenja 400SC (15.5 fl oz/acre)



Mode of action and resistance are critical SENSITIVE Resistant

Not inoculated







Inoculated



Inoculated FRAC 7





Inoculated



Inoculated

Resistant Inoculated FRAC 11













Resistance Frequency in Mid-Atlantic

FRAC 11 (Azoxystrobin)

Sensitivity	CA	CG
Resistant	40%	100%
Moderately Resistant	7%	0%
Sensitive	53%	0%

FRAC 1 (Thiophanate-methyl)

Sensitivity	CC	
Resistant	63%	
Moderately Resistant	0%	
Sensitive	36%	

Fungicide Efficacy and Resistance



How to preserve good chemistries with effective control?

- Rotate modes of action
- Utilize multi-site and bio-rational fungicides during lower disease pressure
- Apply only when absolutely necessary
 - Not necessary during dry periods
 - Only between bloom and harvest for fruit rot
 - Use models

Disease prediction models for AFR and BFR

- Strawberry Advisory System (StAS) developed in Florida (Pavan et al. 2011, MacKenzie and N. A. Peres 2012)
 - On average 40% reduced fungicide use compared to (weekly) calendar sprays
 - No significant differences in marketable yield

- AFR and BFR Models available on NEWA
 - https://newa.cornell.edu/



AFR and BFR models in the Mid-Atlantic?





- Anthracnose is caused by *C. acutatum* and *C gloeosporioides*
 - Fruit and crown rot are detrimental
- Applying correct fungicides is highly important
- Resistance has developed to some chemical classes
 - Prevent resistance by spraying at-risk fungicides wisely

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